

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re the Divisional Patent Application of  
Application No. 09/655,833

Takeshi NOGAMI et al

Conf. No. 8708

Application No.: Not Yet Assigned

Art Unit: 2823

Filed: January 20, 2004

Examiner: F.L. Toledo

For: METHOD FOR PRODUCING SEMICONDUCTOR DEVICE, POLISHING  
APPARATUS, AND POLISHING METHOD

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**PRELIMINARY AMENDMENT**

**MS PATENT APPLICATION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

Prior to examination on the merits, please amend the above-identified U.S. patent application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 13 of this paper.

**Amendments to the Drawings** begin on page 23 of this paper and include both an attached replacement sheet and an annotated sheet showing changes.

**Remarks/Arguments** begin on page 24 of this paper.

An **Appendix** including amended drawing figures is attached following page 24 of this paper.